

**Search Notes**

Application/Control No.

10/710,843

Examiner

Jae Lee

Applicant(s)/Patent under  
Reexamination

LIN ET AL.

Art Unit

2823

**SEARCHED**

Class	Subclass	Date	Examiner

**INTERFERENCE SEARCHED**

Class	Subclass	Date	Examiner

**SEARCH NOTES  
(INCLUDING SEARCH STRATEGY)**

	DATE	EXMR
EAST search: searched for reactive ion etching obviousness	8/6/2007	JML